

PATENT Attorney Docket No.: 3521.165

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of)
) Group Art Unit: 2834
MARK E. WILLIAMS)
) Examiner:
Serial No.: 10/023,144)
)
Filed: December 17, 2001)

For: MAGNETIC LEVITATION STAGE APPARATUS AND METHOD

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Allston L. Jones, Attorney for Applicant

TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT WITHIN THREE MONTHS OF FILING OR BEFORE MAILING OF FIRST OFFICE ACTION (37 CFR 1.97(b))

The information disclosure statement submitted herewith is being filed before the mailing date of a first Office action on the merits. 37 CFR 1.97(b).

The citation listed on the attached PTO 1449, along with the enclosed copies of the references, provides the background and may be material to the examination of the above-identified application and is, therefore, submitted in compliance with the duty of disclosure in 37 C.F.R. 1.56, 1.97 and 1.98.

The Examiner is requested to make the citation of official record in this application.

This Information Disclosure Statement under 37 C.F.R. 1.56 and 1.97 is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that any one or more of these citations constitutes prior art.

If fees are required with the filing of these documents, the Commissioner is authorized to charge such fees to Deposit Account No. 16-1331.

Respectfully submitted,

Allston L. Jones (Reg. No. 27,906)

Attorney of Record

PETERS, VERNY, JONES & SCHMITT, L.L.P. 385 Sherman Avenue, Suite 6 Palo Alto, CA 94306-1840 TEL 650/324-1677 FAX 650/324-1678 Atty Dkt. 3521.165 (ALJ)

Date: April 11, 2002

FOR PTO-1449 (Modified)

QISTO SPATENTS AND PUBLICATIONS FOR APPLICANTS INFORMATION DISCLOSURE STATEMENT

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ATTY. DOCKET NO.	SERIAL NO.
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APPLICANT MARK E. WILLIAMS

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	E		M. E. Williams et al., Magnetic Levitation Scanning Stages for Extreme Ultraviolet Lithography, ASPE 14th annual meeting, Monterey CA., November 1999											
	F			John B. Wronosky, et al., Wafer and Reticle Positioning System for the Extreme Ultraviolet Lithography Engineering Test Stand, SPIE, February 2000										
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